

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Isamu Kobori, et al.                      Art Unit :                      Unknown  
Serial No. : New Divisional Application              Examiner :                      Unknown  
Filed : November 17, 2003                      Conformation No.:              Unknown  
Title : METHOD OF MANUFACTURING A SEMICONDUCTOR METHOD OF  
MANUFACTURING A THIN-FILM TRANSISTOR AND THIN-FILM  
TRANSISTOR

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Under 35 USC §120, this application relies on the earlier filing dates of U.S. application serial no. 10/623,581, filed July 22, 2003, which is a divisional of U.S. application serial no. 09/016,999, filed February 2, 1998, which is a divisional of U.S. application serial no. 08/623,506, filed March 28, 1996. The attached list of references were submitted to the Office in the prior applications and, therefore, are not provided in this application.

This statement is being filed with the application. Please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 11/17/03

  
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Substitute Form PTO-1449 (Modified)  <b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary)  (37 CFR §1.98(b))	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. <b>07977-024004</b>	Application No.
	Applicant <b>Isamu Kobori et al.</b>		
	Filing Date	Group Art Unit	

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	5,413,958	05/95	Imahashi, et al.			
	AB	5,529,630	06/96	Imahashi, et al.			
	AC	5,595,923	01/97	Zhang, et al.			
	AD	5,712,191	1/27/98	Nakajima, et al.			
	AE	5,731,613	3/24/98	Yamazaki, et al.			
	AF	5,767,930	06/98	Kobayashi, et al.			
	AG	5,854,494	05/95	Yamazaki, et al.			
	AH	5,854,096	12/98	Ohtani, et al.			
	AI	5,937,282	8/10/99	Nakajima, et al.			
	AJ	5,959,313	9/28/99	Yamazaki, et al.			
	AK	5,966,594	10/99	Adachi, et al.			
	AL	6,051,453	04/2000	Takemura			
	AM	6,071,764	06/2000	Zhang, et al.			
	AN						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AO	05, 009,089 A	01/1993	Japan				
	AP	01-222432	09/05/89	Japan			ABS	
	AQ	06-260643	09/16/94	Japan			ABS	
	AR	2-150017	06/08/90	Japan			ABS	
	AS	2-224255	09/06/90	Japan			ABS	
	AT	6-84793	03/25/94	Japan			ABS	
	AU	6-124962	05/06/94	Japan			ABS	
	AV							

**Other Documents (include Author, Title, Date, and Place of Publication)**

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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		Filing Date	Group Art Unit

Examiner Initial	Desig. ID	Document
	AW	Y. Fukushima, et al., "A Poly-Si TFT Process for High Speed and Low Voltage CMOS Circuits", Extended Abstracts of the 1993 International Conference on Solid State Devices and Materials, Makuhari, pp. 993-995, 1993.
	AX	

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